

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Satoru Okamoto	Art Unit :	1765
Serial No. :	10/689,617	Examiner :	Mahmoud Dahimene
Filed :	October 22, 2003	Conf. No. :	4799
Title :	METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

REPLY TO ACTION OF MAY 11, 2007

Please amend the above-identified application as follows:

Amendments to the Claims begin on page 2.

Remarks begin on page 25.